

## Walter J. Trybula, Ph.D., BIOGRAPHICAL SKETCH



**Walt Trybula, Ph.D., MBA**, IEEE Fellow & SPIE Fellow, IEEE Distinguished Lecturer is a Director of the *Trybula Foundation, Inc.*, and an Adjunct Professor in the Ingram School of Engineering at Texas State University. He is a technology futurist whose is involved in developing technology choices for emerging technological requirements. He has experience in research of emerging technologies, developing specific applications and products, and building and running production operations. His work in semiconductors, nanotechnology, and energy has been with companies that ranged from start-ups to Fortune 10 corporations.

Dr. Trybula has worked at the leading edge of technology throughout his career. In 2003, the IEEE-USA had him present the advantages of nanotechnology to the US Senate staffers. He was the Semiconductor Industry's team leader of the world-wide effort that resulted in immersion Lithography for the semiconductor industry. Walt has been involved in the International Roadmap of Devices and Systems (IRDS is the replacement for the ITRS) with both the Litho Technical Working Group (TWG) and the Simulation and Modeling TWG over the last 25 years.

*[The "hat" is my brand. People expect me to be wearing one of my hats.]*